



Flexible Platinum nanoparticle strain sensors

E. Skotadis, D. Mousadakos, J. Tanner , P. Broutas, D. Tsoukalas,

Dept. of Applied Physics, National Technical University of Athens
15780 Zographou, GR



Outline

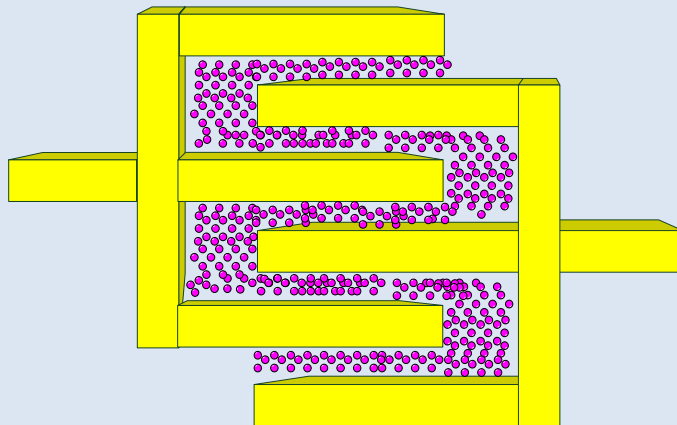
- Interest for sensors fabricated at room-temperature
- Vacuum deposited nanoparticles
- Strain sensors on silicon and flexible substrates
- Conclusions



Motivation

- Co-integration of sensors with electronics requires sensor fabrication at low temperature
- If in addition the sensor can be demonstrated on a flexible substrate new application opportunities can emerge
- Metallic nanoparticles based sensors might present such opportunities

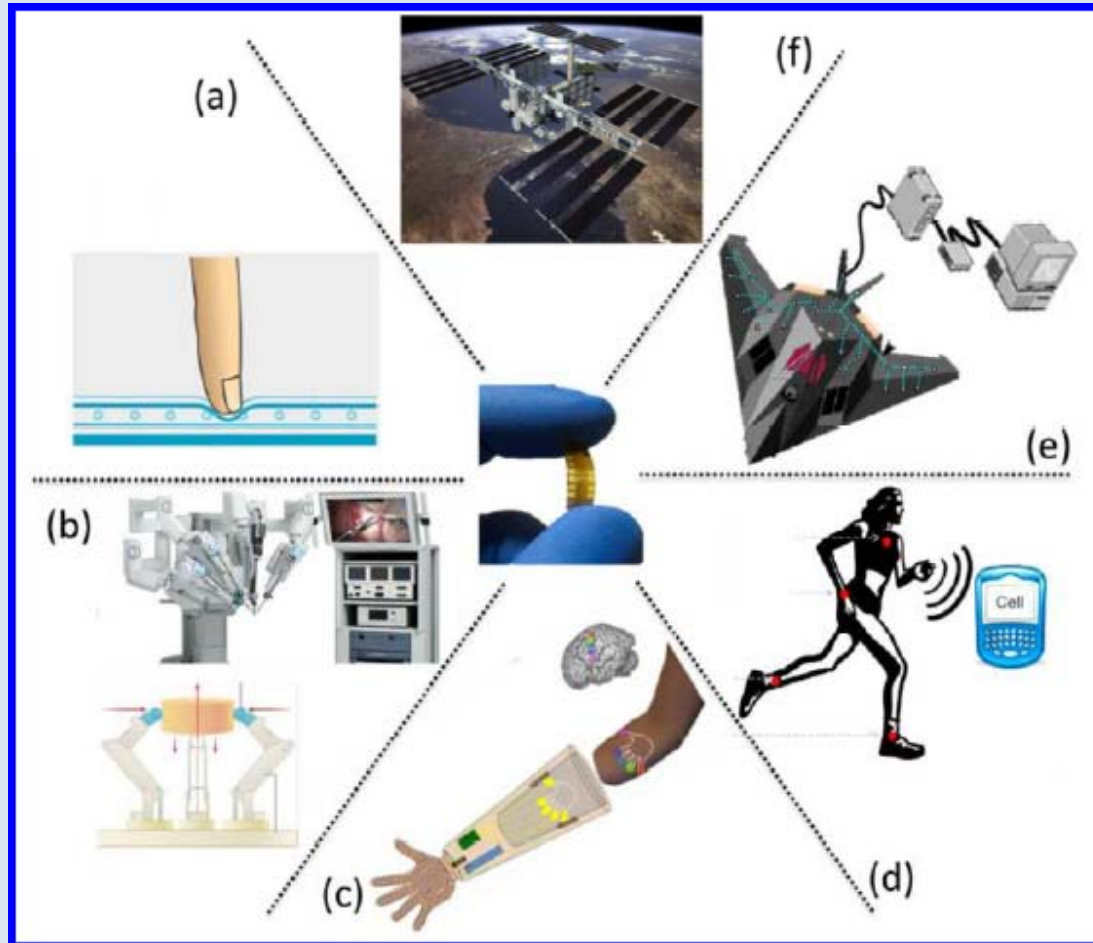
The sensor



- Nanoparticles form a conductive network between two interdigitated (IDE) electrodes
- The electrodes are formed by metal deposition and lithography



Applications

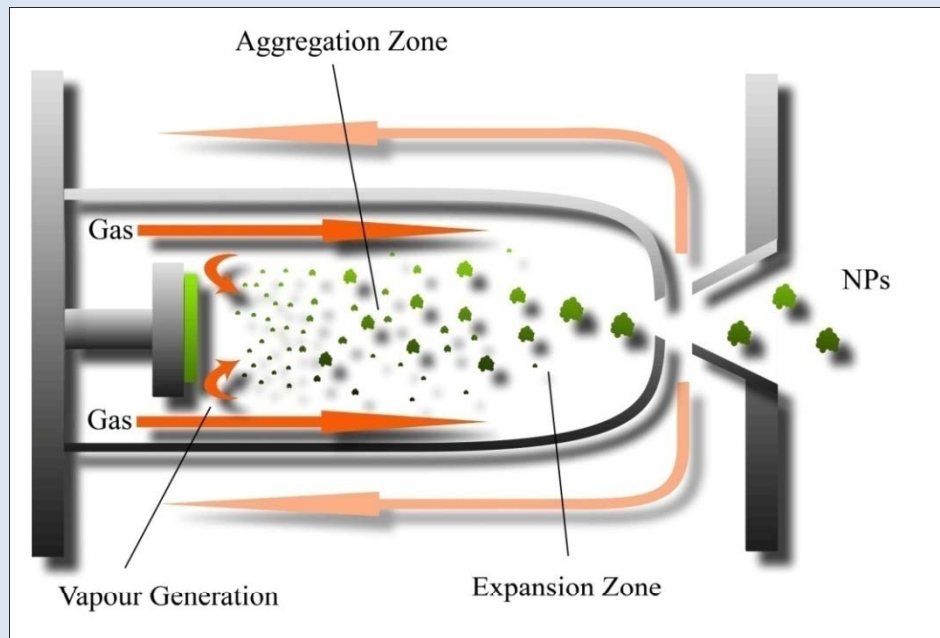


- (a) Touch screen
- (b) E-skin for robotics
- (c) E-skin for prosthetic limbs
- (d) Wearable sensors
- (e) , (f) Space applications and structural health monitoring

Review Paper: M. Segev-Bar and H. Haick, ACS nano, Sept. 2013



Nanoparticle Source

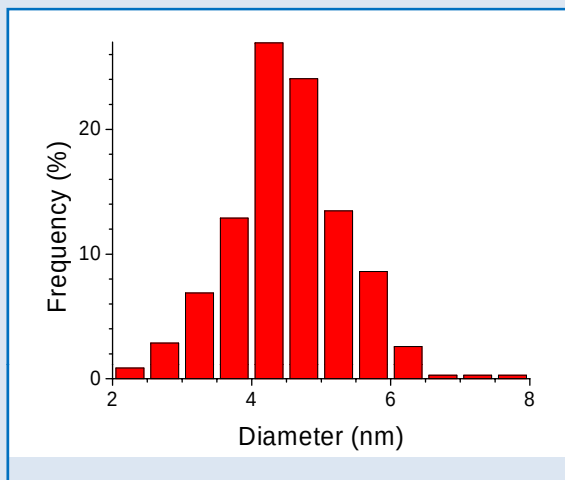


We have investigated electrostatic self-assembly of nanoparticles and Ostwald-ripening:

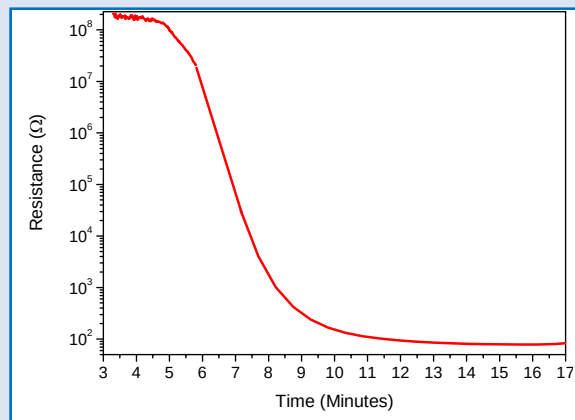
- *Nanotechnology* 20 365605 (2009)
- *Nanotechnology* 22 235306 (2011)
- *J. Materials Research, Special Issue on Self-Assembly* (2011)



TEM images of Platinum nanoparticles with various substrate surface coverage



Size distribution

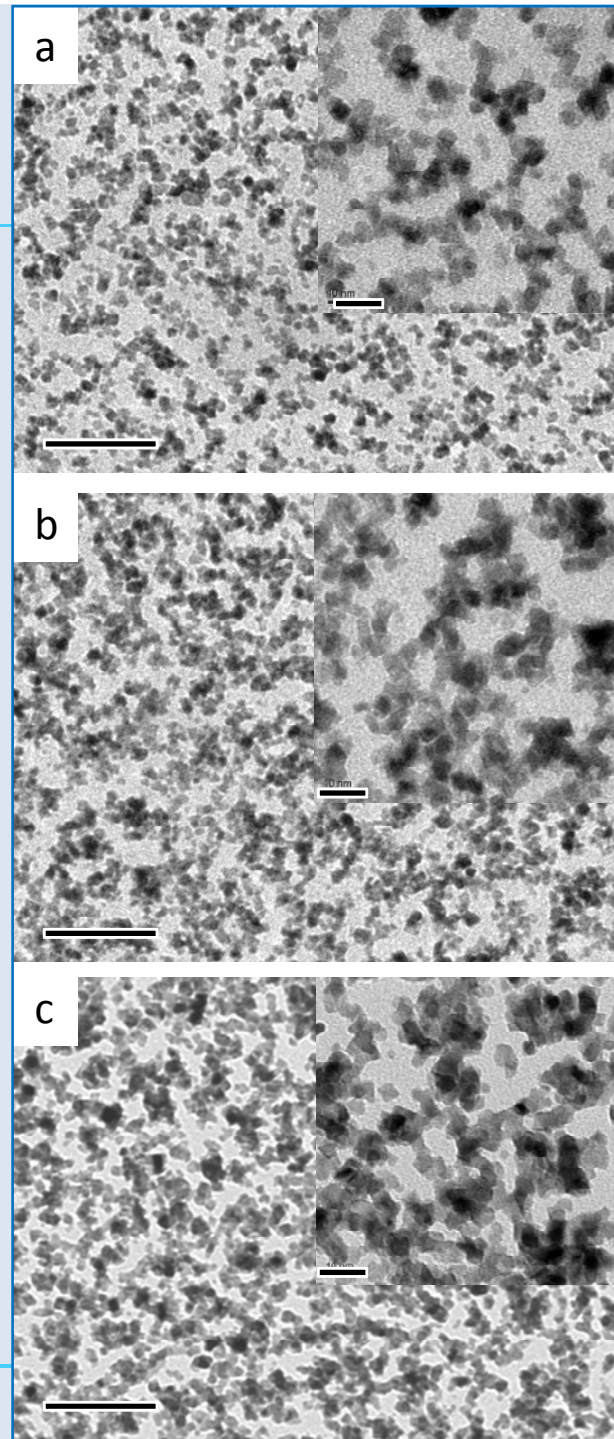


In situ measurement of Resistance

a) 36%

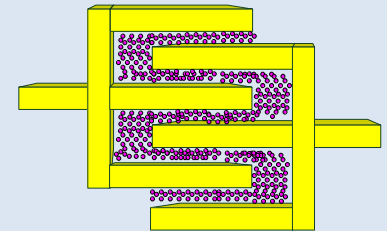
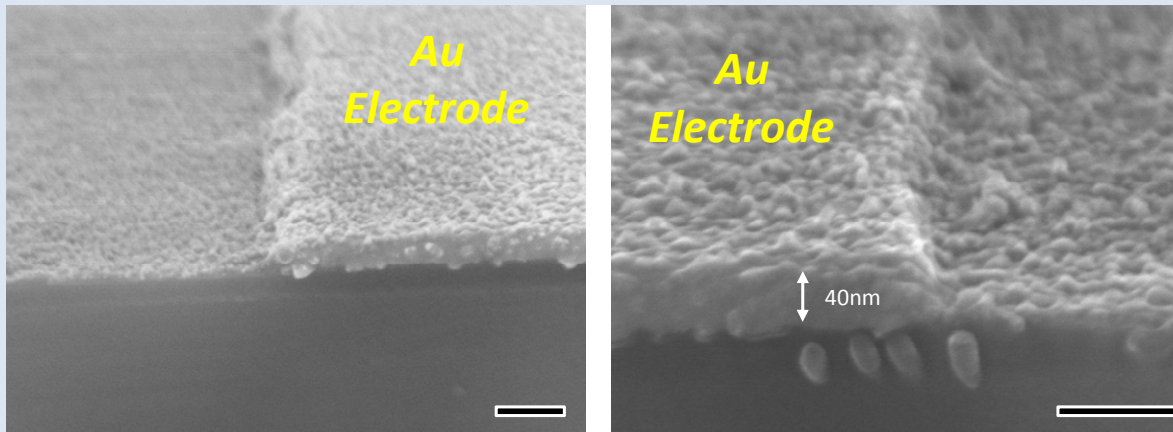
b) 42%

c) 48%





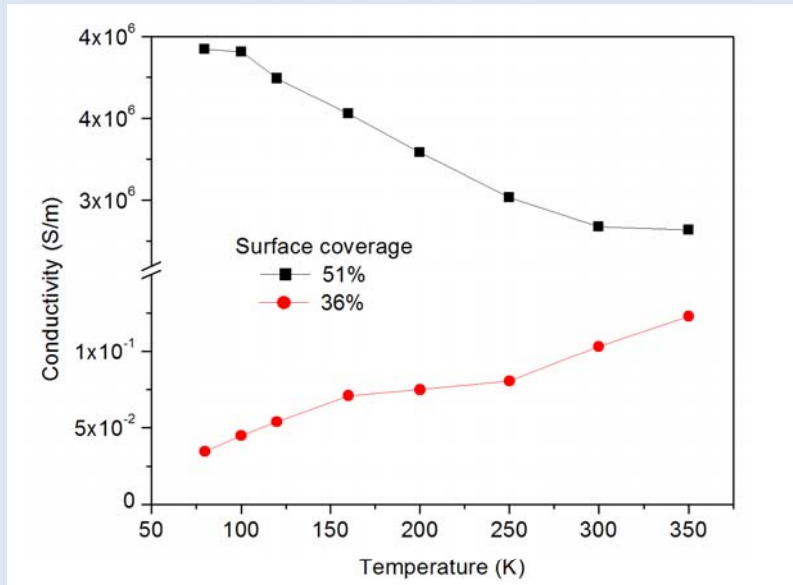
Electrode fabrication



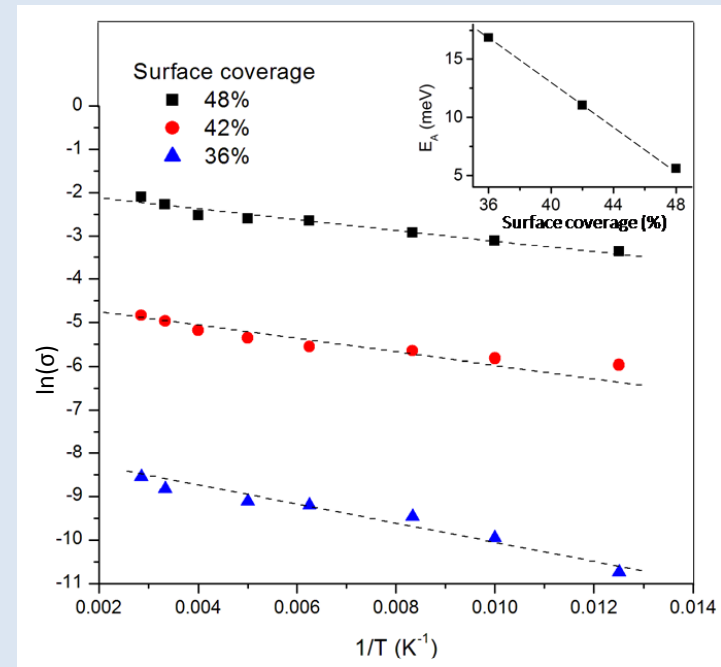
- Gold electrodes formed by e-gun evaporation and lift-off process
- Small electrode thickness needed to avoid shadowing effects during nanoparticle deposition
- Positive slope of electrode pads needed for their efficient electrical communication with nanoparticles



Electrical Resistance of nanoparticle assemblies



Conductivity vs. T



- When surface coverage exceeds $\sim 50\%$ a metallic behavior is observed

R $\uparrow$ T



Discussion

For nanoparticle assemblies conductivity can be approximated* by a thermally activated conduction :

$$\sigma \propto \exp(-2d\beta) \exp\left(-\frac{E_a}{RT}\right)$$

d , is the core–core separation

β , is a quantum mechanical tunneling factor

E_a , is the activation energy for charge hopping

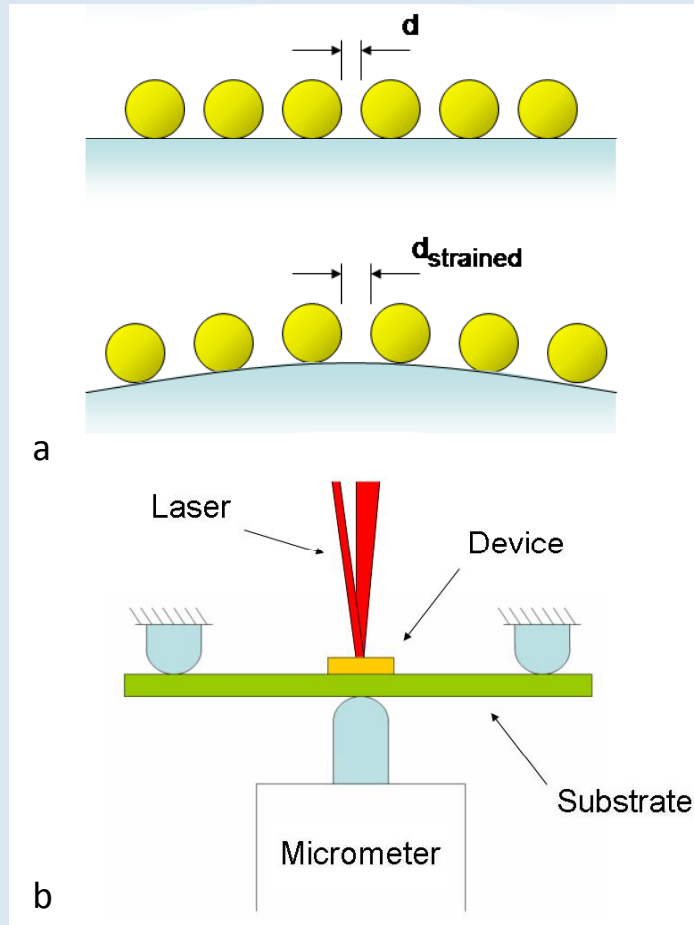
$$E_a = 0.5e^2 \frac{r^{-1} - (r+d)^{-1}}{4\pi\epsilon_r\epsilon_0} \quad r, \text{ radius of nanoparticle}$$

This exponential dependence provides a sensitive detection mechanism for any parameter or process that changes the barrier width

S. Beloborodov, A. V. Lopatin, V. M. Vinokur and K. B. Efetov , Rev. of Modern Physics, April 2007



Demonstration of a strain sensor



$$g = \frac{\Delta R / R}{\varepsilon} = \frac{\Delta R / R}{\Delta L / L}$$

$$\varepsilon = \Delta l / l$$

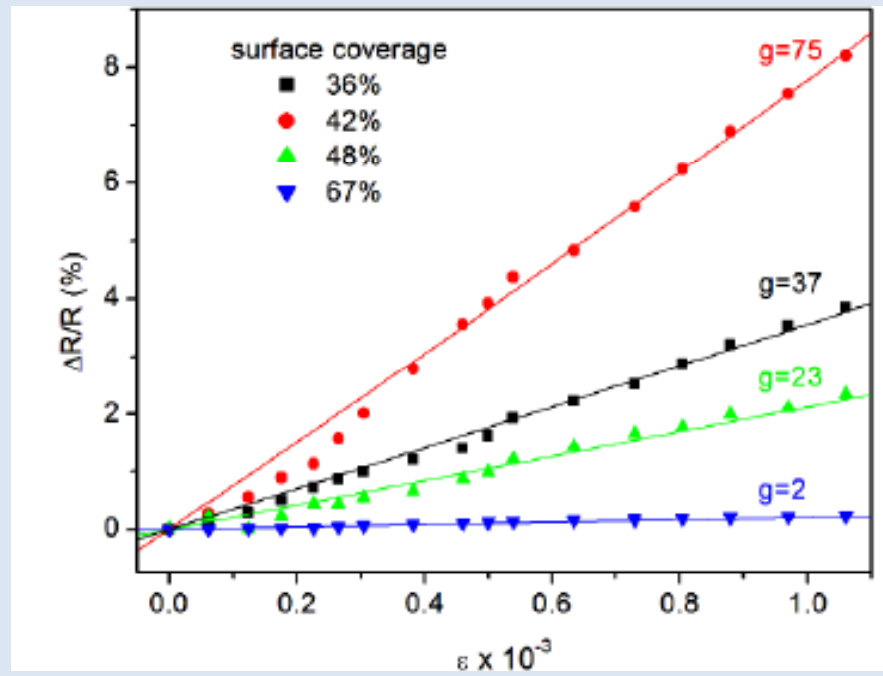
Dramatic increase of gauge factor:
Values of $g > 70$ are obtained
(to compare with $g \sim 2 - 4$ for continuous Pt films)

$$\varepsilon = \frac{T_s}{2R_b}$$

T_s : sample thickness
 R_b : radius of curvature



Results



Relative resistance change as a function of strain of nanoparticle films for various np densities

It can be shown that neglecting the thermally activated term:

$$\Delta R/R = \exp(g\varepsilon) - 1 \quad (1)$$

for $\varepsilon g \ll 1$ (1) simplifies to:

$$\Delta R/R = \varepsilon g \quad (2)$$

Equation (2) is used to draw the lines in figure and estimate gauge factor



Influence of nanoparticle density on strain sensitivity

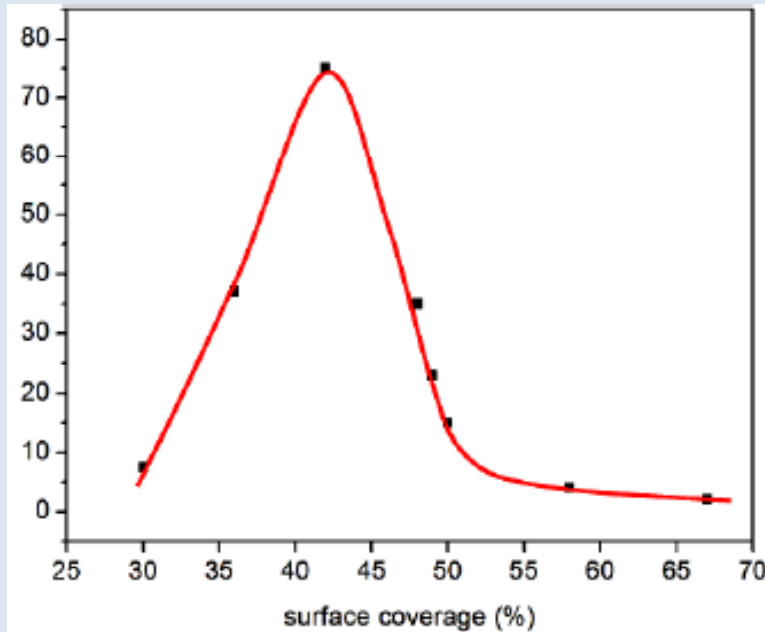


Figure: Gauge factor as a function of surface coverage (experimental results)

Using equation below that does not neglect the thermally activated term we can qualitatively obtain figure results

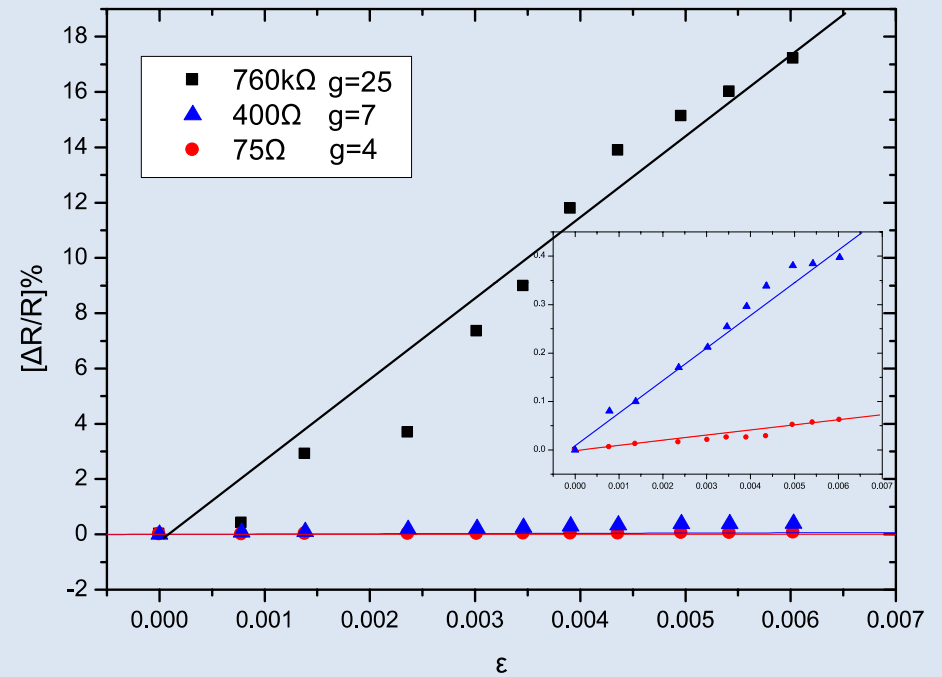
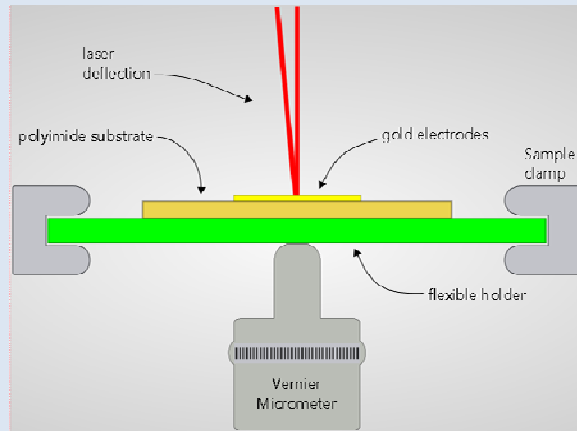
$$\frac{\Delta R}{R} = \exp[(2r + d) \times \beta \varepsilon] \exp \left[7.14 \times \left(\frac{1}{r + d} - \frac{1}{(r + d) + (2r + d) \times \varepsilon} \right) \right] - 1$$

<http://nanotechweb.org/cws/article/lab/50231>

Nanotechnology 23 285501 (2012)



Strain Sensor on Polyimide substrate



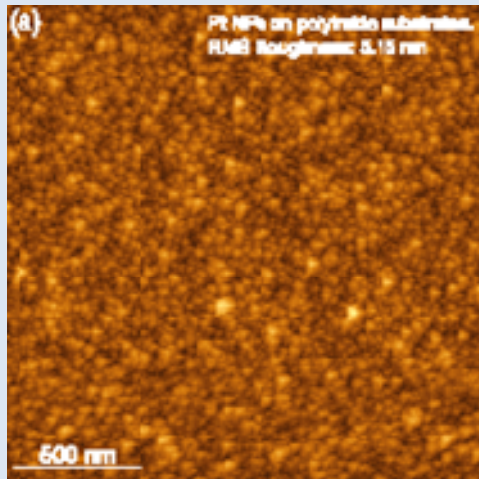
High resistance sample: Gauge Factor estimated at 25

Substrate: Kapton HN, 75 μm thickness



Surface roughness by AFM

SiO₂/Si



5,15 nm RMS roughness

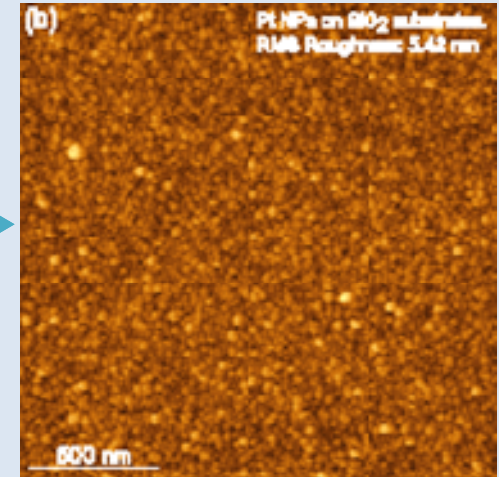
*AFM images following Pt
nanoparticle deposition on :*

SiO₂/Si

← polyimide

Similar roughness values obtained

Poyimide



5,42 nm RMS roughness

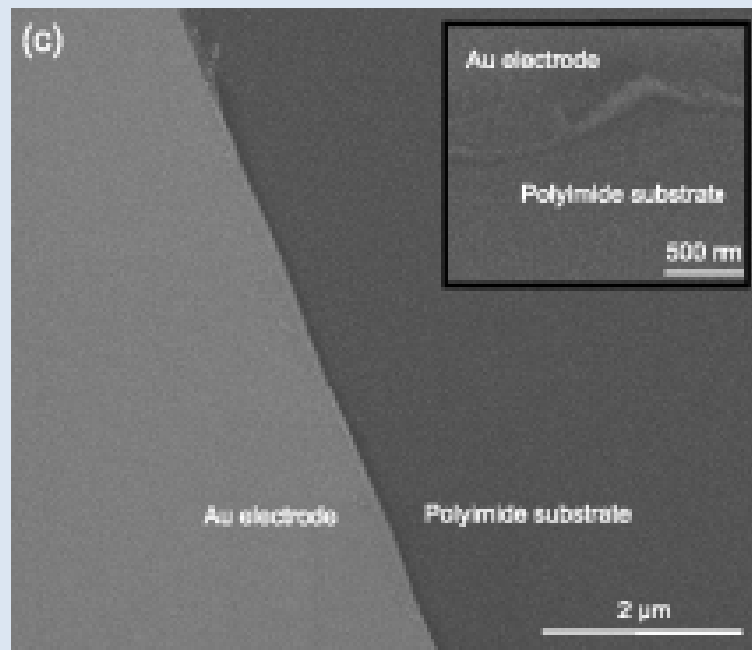
Before nps Deposition

0, 4 nm RMS roughness

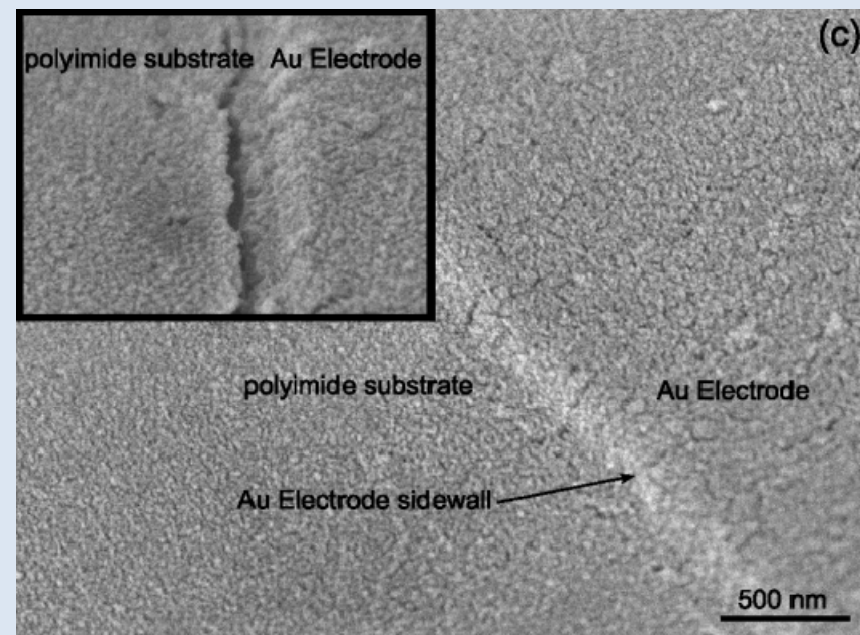
0,6 nm RMS roughness



SEM Images of metallic electrodes on PI



SEM general view of electrode



SEM image showing the existence of cracks on polyimide



Conclusions

- We have investigated room temperature Physical Deposition technique to deposit metallic nanoparticles.
- Either metallic or thermally activated behavior was observed for charge transport in nanoparticle assemblies depending on their density
- By controlling the np density we can optimize the design of sensors through ‘inter-particle space engineering’
- Strain sensors demonstrated on silicon and flexible substrates through this concept



We thank Dr. Giannakopoulos for TEM measurements.

The work was financially supported from:

- **IAPP Marie-Curie Nanosource project, FP7**
- **Herakleitos PhD studentship, MINEDU**

THANK YOU FOR YOUR ATTENTION !